

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Stefan Peter Hau-Riege

Docket No.: IL-11154

Serial No.:

Group Art Unit:

Filed :

Examiner:

For : Method For Characterizing Mask Defects Using
Image Reconstruction From X-Ray Diffraction Patterns

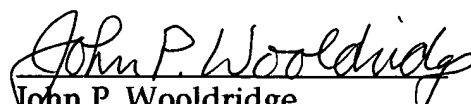
INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Forwarded herewith is an Information Disclosure Statement, Form-1449, in the above-identified application. A copy of the cited references are enclosed.

Respectfully submitted,


John P. Wooldridge
Agent for Applicants
Registration No. 38,725

Dated: February 20, 2004

Enclosure:
As noted above

U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	Atty Docket No. IL-11154	Serial No.
INFORMATION DISCLOSURE STATEMENT STATEMENT BY APPLICANT		Applicant Stefan Peter Hau-Riege
(use several sheets if necessary)		Filing Date Group

U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate

FOREIGN PATENT DOCUMENTS

	Document Number	Date	Country	Class	Subclass	Translation	
						YES	NO

OTHER DISCLOSURES (Including Author, Title, Date, Pertinent Pages, Place of Publication, Etc.)

Examiner	
Examiner: initial if citation considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	